

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 244702US2		SERIAL NO. New Application	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Takeshi YOSHIDA, et al.			
				FILING DATE Herewith		GROUP	
				U.S. PATENT DOCUMENTS			
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
	DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO			
W	AO 2002-189000	07/05/02	Japan				X
	AP						
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
W	AW	Stephen B. IPPOLITO, et al., "HIGH-RESOLUTION IC INSPECTION TECHNIQUE", Department of Electrical and Computer Engineering and the Photonics Center, Boston University, (12 pages)					
W	AX	Stephen B. IPPOLITO, et al., "COMPARISON OF NUMERICAL APERTURE INCREASING LENS AND STANDARD SUBSURFACE MICROSCOPY", Depts. of Physics and Electrical and Computer Engineering and the Photonics Center, Boston University, (2 pages)					
W	AY	Stephen B. IPPOLITO, et al., "HIGH RESOLUTION SUBSURFACE MICROSCOPY TECHNIQUE", Boston University Photonics Center, Depts. of Physics and Electrical and Computer Engineering, (2 pages)					
	AZ						<input type="checkbox"/> Additional References sheet(s) attached
Examiner <i>W. P. ...</i>					Date Considered <i>3/16/05</i>		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							